Analytical solutions to nonlinear oscillations of micro/nano beams using higher-order beam theory

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Abstract. In this study, the nonlinear oscillations of micro/nano beams, modeled by Timoshenko beam theory and actuated by suddenly applied electrostatic forces, are investigated. The effects of electrostatic actuation, residual stress, mid-plane stretching, and fringing field are considered in modeling. In order to develop the governing equations and the boundary conditions, the Hamilton’s principle is employed. After combining governing equations, the Galerkin’s decomposition method is used to convert the governing nonlinear partial equation to a nonlinear ordinary differential equation. The Homotopy Analysis Method (HAM) is used to present semi-analytical solutions to the strongly nonlinear behavior of system. To verify the present model, in special limiting cases, the results are compared with numerical results; and in low values of beam thickness, the results are compared with those obtained with the assumption of Euler-Bernoulli beam theory, which are available in literature. Some numerical results are presented to investigate the effects of high thicknesses and different values of residual stress on the nonlinear frequency and the midpoint deflection of the beam.

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1. Introduction

One of the most significant phenomena associated with micro/nano electromechanical systems, actuated by electrostatic forces, is known as pull-in instability phenomenon, which has been investigated by many researchers. Nathanson et al. [1] and Taylor [2] reported pull-in instability in the 1960s. Microbeams actuated with electrostatic forces are widely used for different applications such as signal filtering and mass sensing [3].

When the applied voltage exceeds a critical value, called pull-in voltage ($V_{pi}$), the flexible microbeam deflects toward the rigid plate. In microbeams, pull-in instability continues to become increasingly important for the design of electrostatic MEMS and NEMS devices. Pull-in analysis can be categorized into two groups according to its state. When the rate of voltage variation is low, inertia has no effect on the microsystem behavior and the critical value of voltage is known as static pull-in voltage ($V_{ps}$). In contrast, when the rate of voltage variation is considerable, the effect of inertia must be taken into account and the critical voltage value is called dynamic pull-in voltage ($V_{pdd}$). The pull-in instability associated with this situation is called dynamic pull-in instability [4,5]. More details about this phenomenon are given in [6-14].

In most nonlinear studies, structures are modeled by Euler-Bernoulli theory. Moghimi Zand et al. obtained pull-in voltage of a microbeam considering the Euler-Bernoulli beam theory [10]. In another study, Moghimi
Zand et al. studied nonlinear frequency of the nonlinear vibration of a microbeam considering Euler-Bernoulli beam theory [16]. The large deformation of an Euler-Bernoulli beam subjected to an arbitrary distributed load was investigated by Malekie et al. [17]. Sedighi et al. investigated the nonlinear dynamics of a Nano-bridge pull-in instability considering the centrifugal force and the rarefied gas flow [18]. Farrokhabadi et al. analyzed the influence of the Casimir force on pull-in instability of nanowires and nanotubes [19]. In some limited studies, microbeams and microwires were modeled by Timoshenko beam theory [17]. The effects of rotary inertia and shear deformation on the nonlinear free vibration of a microbeam were analyzed by Ramezani et al. [20]. Aghari et al. developed governing equations of a microbeam with the assumption of Timoshenko theory, based on the couple stress theory, and analyzed its nonlinear free vibrations [21]. Moghimian and Ahmadian numerically investigated nonlinear vibration of a microplate actuated by electrostatic force with considering the effect of squeeze film damping. They employed the first-order shear deformation theory to model the microplate [11]. For further studies on MEMS/NEMS, please see [22-37].

To solve the nonlinear equations of MEMS, both numerical and semi-analytical methods have been utilized. In the numerical methods, stability and convergence of the solution should be considered because neglecting this issue can result in inappropriate results. Some numerical methods used in this field can be mentioned as Generalized Differential Quadrature method (GDQ) [38], Finite Element method [12], and Shooting method [39]. On the other hand, semi-analytical methods, due to providing a closed-form solution for problems, have been enormously taken into consideration. Among analytical methods, Perturbation method [40] [41] has been mostly used for weak nonlinear problems. The method seeks to find a small parameter and insert it into equation. As a result, finding this parameter is one of its deficiencies [42]. Another analytical method, Homotopy Analysis Method (HAM), which has recently been popular among researchers, is a strong method to solve nonlinear equations. A small parameter is not required in this method. The great trait of this method is controlling sand adjusting of the convergence region. This method was presented by Liao in 1992 [43,44]. In a new study, Daneshpajooh and Moghimian Zand investigated dynamic behavior of an initially curved microbeam using HAM [45].

In the present study, using Lagrange’s equations, equations of micro/nano beam dynamics, actuated by electrostatic force, are developed. To obtain the governing equations and relevant boundary conditions, Timoshenko beam theory is considered. Afterwards, using Galerkin’s decomposition method, the partial governing equations of motions are converted into nonlinear ordinary differential equations. Hereafter, the Homotopy analysis method is employed to solve the equations and a closed-form solution for each deflection and the frequency of the microbeam is presented. In the next step, some numerical results are presented and the effects of different parameters on the oscillations of the system are investigated. At the end, the applications and summary are presented.

2. Formulation

Figure 1 shows an electrostatically actuated microsystem consisting of a clamped-clamped microbeam suspended above a substrate. Through applying voltage, V, between the microbeam and substrate, an attractive electrostatic force results in beam deflection. x, z, \( w \), and \( t \) are the coordinate along the length, the coordinate along the thickness, the deflection in the z-direction, and time, respectively. \( B \), \( \rho \), and \( H \) stand for width, density, and thickness of the microbeam, respectively. \( \varepsilon \), \( I \), and \( d \) represent the vacuum permittivity, the moment of inertia of the cross section about the y-axis, and the initial air gap, respectively.

Regarding the Palmer’s formula, the electrostatic force per unit area is defined as [16]:

\[
F_e = \frac{1}{2} \varepsilon V^2 \left(1 + \frac{\beta}{b} \left(d - w(x,t)\right)\right) .
\]

Consider a Timoshenko beam of length \( L \), constant cross section of \( A \), the mass per unit of \( m \), young modulus \( E \), and shear modulus \( G \) (Figure 1). The displacement field for Timoshenko beam theory is given as follows [46]:

\[
\begin{align*}
    u_1 &= u_0(x,t) - z\varphi(x,t), & u_2 &= 0, & u_3 &= w(x,t),
\end{align*}
\]

![Figure 1. Beam configuration and coordinate system.](image)
where $u_1$, $u_2$, and $u_3$ are displacements along $x$, $y$, and $z$ directions, respectively. $w(x, t)$, $\phi(x, t)$, and $u_0(x, t)$, respectively, are the deflection of the beam in $z$ direction, the angle of rotation of cross section about the $y$ axis with respect to the $z$ direction, and the axial displacement of the middle surface. The non-zero components of Strain tensor are defined as follows:

$$
\varepsilon_x = \frac{\partial u}{\partial x} + \frac{1}{2} \left( \frac{\partial w}{\partial x} \right)^2,
$$

$$
\gamma_{x} = \frac{\partial w}{\partial x} = \phi.
$$

For the non-zero components of stress tensor, we have:

$$
\sigma_x = E\varepsilon_x,
$$

$$
\tau_{x} = G\gamma_{x}.
$$

In the following, the Lagrange method, which is derived from Hamilton's principle, is employed to develop the governing equations and the relevant boundary conditions. The Kinetic energy and potential energy of a beam are respectively given as follows:

$$
T = \frac{1}{2} \int_0^L \left[ m_0 \left( \frac{\partial w}{\partial t} \right)^2 + m_0 \left( \frac{\partial u}{\partial t} \right)^2 + m_2 \left( \frac{\partial \phi}{\partial t} \right)^2 \right] dx,
$$

$$
U = \frac{1}{2} \int_0^L \left[ EI \left( \frac{\partial \phi}{\partial x} \right)^2 + KAG\gamma^2 + EA\varepsilon_x^2 \right] dx,
$$

where:

$$
m_0 = \int_A \rho dA = \rho A, \quad I = \int_A \rho z^2 dA,
$$

$$
m_2 = \int_A \rho z dA = \rho I.
$$

In the Lagrange method [47], to consider external forces which are applied to the system, virtual work done by each of the forces is defined based on the virtual displacements of generalized coordinates as follows:

$$
W_t = \tilde{F} \cdot \tilde{F},
$$

$$
\tilde{F}_w = \tilde{w}(x, t) \tilde{k},
$$

$$\tilde{F} = \tilde{w}(x, t) \tilde{k},
$$

where $W_t$, $\tilde{F}$, $\tilde{F}_w$, and $\tilde{F}_w$ are the work done by total force, the total force vector, the system displacement vector, and the displacements associated with electrostatic force, respectively.

Therefore, virtual work is calculated as follows:

$$
\delta W_t = \tilde{F} \cdot \tilde{\delta r} = (\tilde{F}_w \cdot \tilde{\delta r}) (\delta \tilde{w}(x, t) \tilde{k}) = F_w \delta w(x, t).
$$

The coefficient of each virtual displacement is known as generalized force of the respective coordinate, $Q_q$, where $q$ represents the generalized coordinate. Consequently, we have:

$$
\begin{align*}
Q_w &= F_w, \\
Q_\phi &= 0, \\
Q_u &= 0
\end{align*}
$$

(13)

Lagrangian is defined as [48]:

$$
L = T - U.
$$

(14)

And the general form of Lagrange equation is as follows:

$$
\frac{\partial L}{\partial q} - \frac{\partial}{\partial x} \frac{\partial L}{\partial \dot{q}} - \frac{\partial }{\partial t} \frac{\partial L}{\partial q} = -Q_q.
$$

(15)

For each of the generalized coordinates, Eq. (15) is rewritten as follows:

$$
q = w \rightarrow m_0 \frac{\partial^2 w}{\partial t^2} - \frac{\partial}{\partial x} \left[ KAG \left( \frac{\partial w}{\partial x} - \phi \right) \right]
$$

$$
- \frac{\partial}{\partial x} \left( EA \left[ \frac{\partial u}{\partial x} + \frac{1}{2} \left( \frac{\partial w}{\partial x} \right)^2 \right] \frac{\partial w}{\partial x} \right) = nF_w.
$$

(16)

$$
q = \phi \rightarrow m_2 \frac{\partial^2 \phi}{\partial t^2} - \frac{\partial}{\partial x} \left( EI \frac{\partial \phi}{\partial x} \right) = 0.
$$

(17)

Note that longitudinal displacement in beams is trivial; therefore, $m_0 \frac{\partial u}{\partial t}$ is neglected and the governing equations are stated as follows:

$$
m_0 \frac{\partial^2 w}{\partial t^2} - KAG \left( \frac{\partial^2 w}{\partial x^2} - \frac{\partial \phi}{\partial x} \right) - N \frac{\partial^2 w}{\partial x^2} = bF_w,
$$

(19a)

$$
m_2 \frac{\partial^2 \phi}{\partial t^2} - EI - KAG \left( \frac{\partial w}{\partial x} - \phi \right) = 0.
$$

(19b)

where:

$$
N = N_s + \frac{EA}{2L} \int_0^L \left( \frac{\partial w}{\partial x} \right)^2 dx,
$$

(20)

in which $N_s$ is the initial (residual) axial load.

The kinematic boundary conditions and the initial conditions for the microbeam are respectively given as:

$$
w(0, t) = 0, \quad w(L, t) = 0, \quad \frac{\partial w}{\partial x}(0, t) = 0, \quad \frac{\partial w}{\partial x}(L, t) = 0.
$$

(21)
\[ w(x, 0) = 0, \quad \frac{\partial w}{\partial t}(x, 0) = 0, \]
\[ \phi(x, 0) = 0, \quad \frac{\partial \phi}{\partial t}(x, 0) = 0. \] (22)

The Taylor’s series approximation of \( F_e \) in Eq. (1) can be written as (the order of approximation is 4):
\[
F_e = \frac{1}{2} \varepsilon V^2 \left( 1 + \frac{d}{B} - \frac{w(x, t)}{B} \right)^2 \\
= \frac{1}{2} \varepsilon V^2 \left( \frac{1}{d^5} + \frac{2w(x, t)}{d^5} + \frac{3w(x, t)^2}{d^5} \\
+ \frac{4w(x, t)^3}{d^5} + \frac{5w(x, t)^4}{d^5} \right) + \frac{1}{2} \varepsilon V^2 \left( \frac{1}{d} \right) \\
+ \frac{w(x, t)}{d^2} + \frac{w(x, t)^2}{d^3} + \frac{w(x, t)^3}{d^4} + \frac{w(x, t)^4}{d^5} \right) (23)
\]

Through combining Eqs. (19a) and (19b) and making some mathematical simplifications, we arrive at the following partial equation which governs the beam deflection:
\[
T(w) = a_{20} \frac{\partial^4 w}{\partial x^4} + a_{21} \frac{\partial^4 w}{\partial x^2 \partial y^2} + a_{22} \frac{\partial^2 w}{\partial x^2} \\
+ a_{23} \frac{\partial^2 w}{\partial x^2} + a_{24} \left( \frac{\partial w}{\partial x} \right)^2 + a_{25} \frac{\partial w}{\partial x} \\
+ a_{30} \left( \frac{\partial w}{\partial x} \right)^2 + a_{31} \frac{\partial w}{\partial x} \\
+ a_{32} \frac{\partial^4 w}{\partial x \partial y^2} + a_{33} \frac{\partial w}{\partial x} + a_{34} \frac{\partial^2 w}{\partial x^2} \\
+ a_{35} \frac{\partial^2 w}{\partial x^2} + a_{36} \frac{\partial^2 w}{\partial x^2} \\
+ a_{37} \frac{\partial^2 w}{\partial x^2} + a_{38} \frac{\partial w}{\partial x} \\
+ a_{39} \frac{\partial^2 w}{\partial x^2} + a_{40} \frac{\partial^2 w}{\partial x^2} + a_{41} \frac{\partial^2 w}{\partial x^2} + a_{42} \frac{\partial^2 w}{\partial x^2} = \frac{t}{t^*}. \] (27)

\( t^* = \sqrt{\frac{mL^4}{EI}} \) (26)

Using Eq. (25), the governing equation is rewritten as:
\[
T(\dot{w}) = \frac{\partial^4 \dot{w}}{\partial x^4} + \frac{\partial^2 \dot{w}}{\partial x^2} + b_1 \frac{\partial \dot{w}}{\partial x} + b_2 \frac{\partial^2 \dot{w}}{\partial x^2} + b_3 \frac{\partial \dot{w}}{\partial x} \\
+ b_4 \frac{\partial \ddot{w}}{\partial x^2} + b_5 \frac{\partial^2 \ddot{w}}{\partial x^2} + b_6 \frac{\partial \ddot{w}}{\partial x} + b_7 \frac{\partial \ddot{w}}{\partial x}^2 \\
+ b_8 \frac{\partial \ddot{w}}{\partial x} + b_9 \frac{\partial \ddot{w}}{\partial x^2} + b_{10} \ddot{w}^2 \\
+ b_{11} \ddot{w} \left( \frac{\partial \ddot{w}}{\partial x} \right)^2 + b_{12} \frac{\partial \ddot{w}}{\partial x} + b_{13} \ddot{w} \\
+ b_{14} \ddot{w}^3 + b_{15} \ddot{w}^4 + b_{16} \ddot{w}^4 + b_{17} + b_{18} \ddot{w}^4 \\
+ b_{19} \left( \frac{\partial \ddot{w}}{\partial x} \right)^2 + b_{20} \frac{\partial \ddot{w}}{\partial x} + b_{21} \ddot{w} \left( \frac{\partial \ddot{w}}{\partial x} \right)^2 \\
+ b_{22} \ddot{w}^2 \left( \frac{\partial \ddot{w}}{\partial x} \right)^2 + b_{23} \frac{\partial \ddot{w}}{\partial x} + b_{24} \ddot{w}^3 = 0. \] (27)

Coefficients \( b_1 - b_{24} \) are presented in Appendix B. The dimensionless Kinematic boundary conditions and initial conditions are defined as:
\[
\dot{w}(0, \hat{t}) = 0, \ddot{w}(1, \hat{t}) = 0 \quad \frac{\partial \dot{w}}{\partial x}(0, \hat{t}) = 0, \quad \frac{\partial \ddot{w}}{\partial x}(1, \hat{t}) = 0, \] (28)
\[
\ddot{w}(\hat{x}, 0) = 0 \quad \ddot{w}(\hat{x}, 1) = 0. \] (29)

In order to solve Eq. (27), the deflection of the beam is assumed to be the product of two separated functions as follows:
\[
\ddot{w}(\hat{x}, \hat{t}) = \phi(\hat{x}) \psi(\hat{t}), \] (30)

where \( \phi(\hat{x}) \) is a trial function which satisfies the kinematic boundary conditions and \( \psi(\hat{t}) \) is an unknown time-dependent function. \( \phi(\hat{x}) \) can be defined as:
\[
\phi(\hat{x}) = \hat{x}^2 (1 - \hat{x})^2. \] (31)

The one-parameter Galerkin’s solution can be computed by:
\[
\int_0^1 \phi(\hat{x}) T(\ddot{w}(\hat{x}, \hat{t})) d\hat{x} = 0. \] (32)

After substituting Eqs. (27) and (31) in Eq. (32) and
integrating them, the governing equation for \(u(t)\) is obtained as follows:
\[
\begin{align*}
(1) & + (a_1 + a_13 V^2)\ddot{u} + (a_2 + a_14 V^2)u + a_3 V^2 u^2 \\
& + (a_4 + a_15 V^2) u^3 + a_5 V^2 u^4 + a_6 V^2 \dddot{u} \\
& + a_7 V^2 u^2 \dddot{u} + a_8 V^2 u^2 \dddot{u} + a_9 V^2 u^4 + (a_{10}) \\
& + a_{11} V^2 u^2 \dddot{u} + a_{11} V^2 a^3 \dddot{u} + a_{12} V^2 = 0. \quad (33)
\end{align*}
\]
\(a_{1} - a_{16}\) are given in Appendix C. The initial conditions are mentioned as:
\[
\begin{align*}
u(0) = 0, \quad \dot{u}(0) = 0, \quad \dddot{u}(0) = 0, \quad \dddot{u}(0) = 0. \quad (34)
\end{align*}
In the next section, the homotopy analysis method is employed to solve Eq. (33).

3. Application of homotopy analysis method to the problem

In this section, initially, a brief description of the homotopy analysis method is presented.

HAM transforms a general nonlinear problem into an infinite number of linear problems by embedding an auxiliary parameter \(q\). Consider the following nonlinear differential equation:
\[
\mathcal{R}(u(t)) = 0, \quad (35)
\]
where \(\mathcal{R}\) is a nonlinear operator and \(u(t)\) is an unknown function. Using \(q \in [0, 1]\) as an embedding parameter, the defined homotopy is introduced as follows [44]:
\[
\begin{align*}
\mathcal{H} (\Phi; q, h, H(t)) &= (1 - q) \mathcal{L} \left[ \Phi(t; q) - u_0(t) \right] \\
& - q h H(t) \mathcal{R} \left[ \Phi(t; q), f_1(q), h(q) \right]. \quad (36)
\end{align*}
\]
where \(u_0(t)\), \(H(t)\), \(\mathcal{L}\), and \(\mathcal{R}\) stand for non-zero auxiliary parameter, an initial guess, non-zero auxiliary function, auxiliary linear operator, and nonlinear operator, respectively. Values of \(h\) and \(H(t)\) adjust the convergence region of the solution. For a microbeam problem, the auxiliary function is 1.

Considering Eq. (33), the nonlinear operator may be written as:
\[
\begin{align*}
\mathcal{R} \left[ \Phi(t; q), f_1(q), h(q) \right] &= \frac{\partial^4 \Phi(t; q)}{\partial t^4} + (f_1(q) \\
& + h(q)) \frac{\partial^3 \Phi(t; q)}{\partial t^2} + f_1(q) h(q) \Phi(t; q) \\
& + a_3 V^2 \Phi(t; q)^2 + (a_4 + a_15 V^2) \Phi(t; q)^3 \\
& + a_5 V^2 \Phi(t; q)^4 + a_6 V^2 \left( \frac{\partial \Phi(t; q)}{\partial t} \right)^2 \\
& + a_7 V^2 \Phi(t; q)^2 \left( \frac{\partial \Phi(t; q)}{\partial t} \right)^2 \\
& + a_8 V^2 \Phi(t; q)^2 \\
& + a_9 V^2 \Phi(t; q)^2 \frac{\partial^2 \Phi(t; q)}{\partial t^2} \\
& + a_{10} V^2 \Phi(t; q)^2 \frac{\partial^2 \Phi(t; q)}{\partial t^2} \\
& + a_{11} V^2 \Phi(t; q)^2 \frac{\partial^2 \Phi(t; q)}{\partial t^2} \\
& + a_{12} V^2. \quad (37)
\end{align*}
\]
Note that:
\[
\begin{align*}
f_1(1) &= \frac{(a_1 + a_13 V^2)}{2} \sqrt{\frac{(a_1 + a_13 V^2)}{4} - (a_2 + a_14 V^2)}, \\
h_1(1) &= \frac{(a_1 + a_13 V^2)}{2} \sqrt{\frac{(a_1 + a_13 V^2)}{4} - (a_2 + a_14 V^2)}. \quad (38)
\end{align*}
\]
The homotopy linear operator is assumed as:
\[
\mathcal{L}[\Phi(t; q)] = \frac{\partial^4 \Phi(t; q)}{\partial t^4} + (\omega^2 + \nu^2) \frac{\partial^2 \Phi(t; q)}{\partial t^2} + \omega^2 \nu^2 \Phi(t; q), \quad (39)
\]
in which \(\omega\) and \(\nu\) are the bending and the rotary natural frequencies, respectively. Note that the bending natural frequency is only investigated in this study. The functions \(\Phi(t; q), f_1(q)\), and \(h_1(q)\) can be expanded as:
\[
\begin{align*}
f_1(q) &= \omega^2 + \omega_1(\omega)q + \omega_2(\omega)q^2 + \omega_3(\omega)q^3 + \omega_4(\omega)q^4 + \ldots \\
h_1(q) &= \nu^2 + \nu_1(\nu)q + \nu_2(\nu)q^2 + \nu_3(\nu)q^3 + \nu_4(\nu)q^4 + \ldots \\
\Phi(t; q) &= u_0(t) + u_1(t)q + u_2(t)q^2 + u_3(t)q^3 \\
& + u_4(t)q^4 + u_5(t)q^5 + u_6(t)q^6 + \ldots \quad (40)
\end{align*}
\]
By equating Eq. (36) with zero, the zero-order deformation equation is obtained as:
\[
(1 - q) \mathcal{L} \left[ \Phi(t; q) - u_0(t) \right] = q h H(t) \mathcal{R} \left[ \Phi(t; q), f_1(q), h(q) \right]. \quad (43)
\]
\[
\Phi(0; q) = 0, \quad \frac{\partial \Phi(0; q)}{\partial t} = 0, \quad \frac{\partial^2 \Phi(0; q)}{\partial t^2} = 0, \quad \frac{\partial^3 \Phi(0; q)}{\partial t^3} = 0, \quad (44)
\]
when \(q = 0\), we arrive at:
\[
\mathcal{L} \left[ \Phi(t; q) - u_0(t) \right] = 0. \quad (45)
\]
Therefore, the zero-order approximation of \(u(t)\) can be calculated.
\( u_t(t) \) can be set to zero. In the next step, with differentiating Eq. (43) and then setting \( q = 0 \), the first-order deformation equation is constructed. Through solving the following equation, the first-order approximation of \( u(t) \) is obtained subject to zero initial conditions:

\[
\mathcal{L}[u_1(t)] = h\mathcal{R} \left[ \Phi(t; q), f_1(q), h_t(q) \right]_{q=0} \tag{46}
\]

The higher-order approximations of the solution \( u(t) \) can be obtained by solving higher-order deformation equations. Differentiating Eq. (43) \( j \) times with respect to \( q \), then setting \( q = 0 \), and finally dividing each side by \( q^j \), the \( j \)th order deformation equation is obtained as follows:

\[
\mathcal{L}[u_j(t) - \chi_j u_{j-1}(t)] = \frac{1}{(j-1)!} h \frac{\partial^{j-1} \mathcal{R} \left[ \Phi(t; q), f_j(q), h_t(q) \right]}{\partial q^{j-1}}_{q=0} \tag{47}
\]

in which \( \chi_j \) is defined:

\[
\chi_j = \begin{cases} 
0 & \text{when } j \leq 1 \\
1 & \text{otherwise} 
\end{cases} \tag{48}
\]

The terms \( \omega_j \) and \( v_j \) are obtained through eliminating the secular terms. It should be noted that vibrations of an undamped microbeam under the action of the electrostatic force can be expressed by the following base functions [16]:

\[
\cos(k \omega t), \cos(k v t) \quad k = 1, 2, 3, \ldots \tag{49}
\]

Therefore, to eliminate the secular term in the \( j \)th order of approximation, the coefficients of \( \cos(k \omega t) \) and \( \cos(kv t) \) in the \((j-1)\)th order deformation equation have to be set to zero. This results in two algebraic equations. Solving these two equations yields \( \omega_{j-2} \) and \( v_{j-2} \) as functions of both \( \omega \) and \( v \). After obtaining sufficient approximations, by setting \( q = 1 \) in Eqs. (40), (41), (42), we arrive at:

\[
f_1(1) = \frac{(a_1 + a_{13} V^2)}{2} - \sqrt{\frac{(a_1 + a_{13} V^2)^2}{4} - (a_2 + a_{14} V^2)}
\]

\[
= \omega^2 + \sum_{j=1}^{p} \omega_j(\omega) = \omega^2 + \omega_1(\omega) + \omega_2(\omega) + \ldots + \omega_p(\omega), \tag{50}
\]

\[
h_1(1) = \frac{(a_1 + a_{13} V^2)}{2} + \sqrt{\frac{(a_1 + a_{13} V^2)^2}{4} - (a_2 + a_{14} V^2)}
\]

\[
= v^2 + \sum_{j=1}^{p} v_j(v) = v^2 + v_1(v) + v_2(v) + \ldots + v_p(v). \tag{51}
\]

\[
u(t) = \sum_{j=1}^{p+2} u_j(t) = u_0(t) + u_1(t) + u_2(t) + \ldots + u_{p+2}(t)
\]

\[+ \ldots + u_{p+2}(t). \tag{52}
\]

where \( p \) is order of approximation. The nonlinear frequencies \( \omega \) and \( v \) can be calculated through simultaneously solving Eqs. (50) and (51), using MATLAB fsolve command. The terms \( u_1(t), u_2(t), \omega_1, \omega_2, v_1, \) and \( v_2 \) are presented in Appendix D.

4. Results and discussion

In this section, some numerical examples are presented to investigate the behavior of a microbeam, actuated by electrostatic force, with general assumption of Timoshenko beam theory. Also, results are compared with those obtained based on the assumption of Euler-Bernoulli beam theory, which is available in literature.

In the first step, in order to validate the model used in this study, some comparisons are made between the present model and the model developed with assumption of Euler-Bernoulli beam theory (available in literature). Moreover, the results obtained by the present model are compared with numerical results. Figure 2(a) and (b) compare the results obtained by the present model with those presented in literature (with assumption of Euler-Bernoulli beam theory). Figure 2(a) and (b) display the variations of the nonlinear frequency with applied voltage and the midpoint deflection time history, respectively. Note that to draw these figures, the parameters are selected as [16]: \( B = 100 \, \mu m, \quad H = 1.5 \, \mu m, \quad \rho = \frac{2330 \, kg}{m^3}, \quad v = 0.28, \quad d = 1.18 \, \mu m, \quad E = 166 \, GPa, \quad \text{and} \quad RS = 6 \, MPa. \) Results provided in Figure 2(a) and (b) show that in slender beams, results of Euler-Bernoulli and Timoshenko beam theories are in close agreement, which are confirmed by the results available in literature [49].

Table 1 presents the calculated [38] and measured [50] initial frequencies for a microbeam in different beam lengths. The results provided in Table 1 also confirm that in beams with the large \( \frac{L}{d} \) ratio, Timoshenko and Euler-Bernoulli beam theories are in good agreement.

Figure 3 illustrates the midpoint deflection of a microbeam with \( L = 150 \, \mu m, \quad B = 50 \, \mu m, \quad d = 2 \, \mu m, \quad H = 7 \, \mu m, \quad \rho = \frac{2330 \, kg}{m^3}, \quad v = 0.28, \quad E = 169 \, GPa, \quad V = 100 \, V, \quad \text{and} \quad RS = 0 \, MPa. \) The beam equation is numerically solved by Runge-Kutta method, using MATLAB software, and the numerical results are presented in Figure 3. It is seen that there exists an excellent agreement between the analytical and numerical results.

The comparisons reveal that the model utilized in this study is reliable. In order to show the difference between Euler-Bernoulli and Timoshenko beam
The nonlinear frequency of the beam as a function of the applied voltage is shown in Figure 2(a). The results are presented for different beam lengths and input voltages, with the nonlinear frequency (Hz) plotted against the voltage (V). The parameters used in the calculations are $L = 550 \mu m$, $B = 50 \mu m$, $\rho = 2230 \frac{kg}{m^3}$, $v = 0.28$, and $d = 1 \mu m$. The graph shows that the nonlinear frequency increases with increasing voltage.

Figure 2(b) shows the midpoint deflection of a microbeam for different input voltages, with the midpoint deflection (m) plotted against time (s). The results are presented for voltages of 20 V and 25 V. The parameters used in the calculations are $L = 550 \mu m$, $B = 50 \mu m$, $\rho = 2230 \frac{kg}{m^3}$, $v = 0.28$, and $d = 1 \mu m$. The graph shows that the midpoint deflection increases with increasing voltage.

Table 3 lists the voltage of pull-in instability corresponding to Figures 4 and 5. The results presented in the table confirm that in thick beams, the differences between the above-mentioned theories are obvious. The effect of residual stress on the nonlinear frequency and the midpoint deflection of a microbeam are depicted in Figure 6(a) and (b). The parameters used in the calculations are $L = 550 \mu m$, $B = 50 \mu m$, $\rho = 2230 \frac{kg}{m^3}$, $v = 0.28$, and $d = 1 \mu m$. The graph shows that the nonlinear frequency increases with increasing voltage.

Figure 7(a) and (b) present the phase portrait for a microbeam with assumptions of Euler-Bernoulli and Timoshenko beam theories, respectively. The parameters used in the calculations are $L = 550 \mu m$, $B = 50 \mu m$, $\rho = 2230 \frac{kg}{m^3}$, $v = 0.28$, and $d = 1 \mu m$. The graph shows that the midpoint deflection increases with increasing voltage.

Figure 8 compares the behavior of a microbeam based on Timoshenko beam theory with that of a microplate based on nonlinear first-order shear deformation theory (FSDT) in different pretension values. Both of them are actuated with the input voltage of 30 V. The parameters used in the calculations are $L = 250 \mu m$, $B = 50 \mu m$, $\rho = 2230 \frac{kg}{m^3}$, $v = 0.28$, and $d = 2 \mu m$. The graph shows that the midpoint deflection increases with increasing voltage.

In HAM, an appropriate value for $h$ parameter has to be found to guarantee the convergence of the solution series. One of the best ways to find this value is to plot $h$-curves. $h$-curves show the variations of solution with respect to $h$. Note that the proper solution should be independent from $h$. Figure 9 depicts the nonlinear frequency versus $h$ in different orders of approximation $p$. It is seen that by setting $h = -1$, we ensure converge of the solution series.
Table 1. Comparison between the experimental and calculated results.

<table>
<thead>
<tr>
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<tbody>
<tr>
<td></td>
<td></td>
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<td></td>
<td></td>
</tr>
<tr>
<td>210</td>
<td>322.05</td>
<td>324.70</td>
<td>324.70</td>
<td>324.78</td>
<td>324.69</td>
</tr>
<tr>
<td>310</td>
<td>163.22</td>
<td>164.35</td>
<td>163.46</td>
<td>163.16</td>
<td>163.13</td>
</tr>
<tr>
<td>410</td>
<td>102.17</td>
<td>103.80</td>
<td>103.70</td>
<td>103.42</td>
<td>103.40</td>
</tr>
<tr>
<td>510</td>
<td>73.79</td>
<td>74.80</td>
<td>73.46</td>
<td>74.38</td>
<td>74.36</td>
</tr>
</tbody>
</table>

Table 2. Comparison between the predictions of Euler-Bernoulli and Timoshenko beam theories for the nonlinear frequency of a micro-beam in different input voltages and beam thicknesses.

<table>
<thead>
<tr>
<th>H (µm)</th>
<th>V (v)</th>
<th>10</th>
<th>25</th>
<th>42</th>
<th>50</th>
<th>100</th>
<th>121</th>
<th>50</th>
<th>200</th>
<th>223</th>
</tr>
</thead>
<tbody>
<tr>
<td></td>
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<tr>
<td>TBT</td>
<td>288.54</td>
<td>278.04</td>
<td>228.06</td>
<td>568.02</td>
<td>518.04</td>
<td>431.46</td>
<td>861.34</td>
<td>742.45</td>
<td>628.18</td>
<td></td>
</tr>
<tr>
<td>EBBT</td>
<td>288.70</td>
<td>278.30</td>
<td>230.77</td>
<td>569.61</td>
<td>519.80</td>
<td>446.74</td>
<td>866.43</td>
<td>749.30</td>
<td>665.26</td>
<td></td>
</tr>
</tbody>
</table>

Figure 4. Comparison between the predictions of Euler-Bernoulli beam theory about the variations of the nonlinear frequency with the input voltage for: (a) Different thicknesses of the beam; (b) the magnification of H = 30 µm; (c) the magnification of H = 20 µm; and (d) the magnification of H = 10 µm.

Table 3. Comparison between predictions of Euler-Bernoulli and Timoshenko beam theories for the voltage of pull-in instability of an actuated microbeam in different beam thicknesses.

<table>
<thead>
<tr>
<th>H (µm)</th>
<th>10</th>
<th>20</th>
<th>30</th>
</tr>
</thead>
<tbody>
<tr>
<td>TBT</td>
<td>46.33 V</td>
<td>130.87 V</td>
<td>240.06 V</td>
</tr>
<tr>
<td>EBBT</td>
<td>46.34 V</td>
<td>131.17 V</td>
<td>240.63 V</td>
</tr>
</tbody>
</table>

5. Conclusions

In this study, the governing equations and the boundary conditions of nonlinear oscillation of micro/nano beams with assumption of Timoshenko beam theory have been developed. The ordinary equation of motion has been built utilizing the
Figure 5. Comparison between the predictions of Euler-Bernoulli and Timoshenko beam theories about the midpoint deflection time history near the voltage of pull-in instability with beam thicknesses of (a) $H = 30 \, \mu m$, (b) $H = 20 \, \mu m$, and (c) $H = 30 \, \mu m$.

Galerkin’s decomposition method. The homotopy analysis method has been employed to solve the governing equation and the present semi-analytical solutions. The results obtained based on the present model have been compared with those obtained by Euler-Bernoulli beam theory. Regarding the presented results for thick beams, Timoshenko beam theory gives us more accurate results, which are in close agreement with experimental results. Furthermore, with increasing the input voltage, the differences between results of Timoshenko and Euler-Bernoulli beam theories increase. Also, comparing the results predicted by FSDT plate and Timoshenko beam, one can note that in low amounts of compressive pretension, these two theories provide approximately the same results. Conversely, in high amounts of compressive pretension, these two theories differ from each other.

Acknowledgments

The authors would like to thank Iranian National Science Foundation (INSF) for their support.
Figure 7. The phase portrait of a microbeam (voltage = 230 V) with assumptions of (a) Euler-Bernoulli theory, and (b) Timoshenko theory.

Figure 8. Comparison between a microbeam (with assumption of Timoshenko theory) and a microplate (with assumption of first-shear deformation theory) under different pretension values with the input voltage of 30 V.

Figure 9. The h-curve of ω for the microbeam actuated by step-input voltage of 100 V.

References


37. Onalad, H.M., Younis, M.I., Absaleem, F.M., Miles,


Appendix A
Coefficients $a_{20} - a_{41}$ are presented as follows:
\[
 a_{20} = I_{33} + N \frac{I_{33}}{F_{11}},
\]
\[
 a_{21} = - \left( \frac{I_{33}}{F_{11}} m + m_2 + m_2 \frac{N}{F_{11}} \right),
\]
\[
 a_{22} = m - 2 m_2 \frac{F_{11} d^3}{F_{11} d^2},
\]
\[
 a_{23} = \frac{2 I_{33} a}{F_{11} d^4} + \frac{b I_{33}}{F_{11} d^4} - N,
\]
\[
 a_{24} = \frac{6 I_{33} a}{F_{11} d^4} + \frac{2 b I_{33}}{F_{11} d^4},
\]
\[
 a_{25} = \frac{3 I_{33}}{F_{11} d^4} \left( \frac{3a}{b} + b \right),
\]
\[
 a_{26} = \frac{4 a}{d} + b,
\]
\[
 a_{27} = \frac{3 I_{33}}{F_{11} d^4} \left( \frac{4a}{d} + b \right),
\]
\[
 a_{28} = \frac{2 m_2}{F_{11} d^3} \left( \frac{3a}{d} + b \right),
\]
\[
 a_{29} = \frac{6 m_2}{F_{11} d^3} \left( \frac{4a}{d} + b \right),
\]
\[
 a_{30} = \frac{m_a m_2}{F_{11}},
\]
\[
 a_{31} = \frac{3 m_2}{F_{11} d^4} \left( \frac{4a}{b} + b \right),
\]
\[
 a_{32} = \frac{2 a}{d^2} - \frac{b}{d^2},
\]
\[
 a_{33} = \frac{4 a}{d^2} - \frac{b}{d^2},
\]
\[
 a_{34} = \frac{5 a}{d^2} + b,
\]
\[
 a_{35} = \frac{12 I_{33}}{F_{11} d^5} \left( \frac{5a}{d} + b \right),
\]
\[
 a_{36} = \frac{12 m_2}{F_{11} d^5} \left( \frac{5a}{d} + b \right),
\]
\[
 a_{37} = - \frac{12 m_2}{F_{11} d^5} \left( \frac{5a}{d} + b \right),
\]
\[
 a_{38} = \frac{4 m_2}{F_{11} d^4} \left( \frac{5a}{d} + b \right),
\]
\[
 a_{39} = - \frac{4 m_2}{F_{11} d^4} \left( \frac{5a}{d} + b \right),
\]
\[
 a_{40} = a \frac{b}{d},
\]
\[
 a_{41} = - \frac{5 a}{d^2} - \frac{b}{d^2},
\]
where $a$, $b$, $I_{33}$, and $F_{11}$ are defined as below:
\[
 a = 1,\quad b = 1,\quad I_{33} = E I,\quad F_{11} = K A G.\]
Appendix B

Coefficient $b_1 - b_{24}$ are presented as follows:

$$b_1 = \left( -\frac{m_0}{F_{11}} - m_2 \right) \times \frac{1}{m_0 L^2},$$

$$b_2 = -\frac{m_2}{F_{11} L^2} \left( \frac{2}{d} + b \right) \times \frac{1}{m_0},$$

$$b_3 = \frac{I_{33}}{F_{11}} \frac{2}{d + b} \times \frac{L^2}{EI},$$

$$b_4 = \frac{N_s}{F_{11}} + EAh^2 \int_0^1 \left( \frac{\partial \hat{w}}{\partial x} \right)^2 \, d\hat{x},$$

$$b_5 = \frac{N_s m_2}{m L^2 F_{11}} - \frac{EAh^2 m_2}{2L^3 F_{11}} \int_0^1 \left( \frac{\partial \hat{w}}{\partial x} \right)^2 \, d\hat{x},$$

$$b_6 = \frac{N_s L^2}{EI} - \frac{EAh^2}{2L^3 F_{11}} \int_0^1 \left( \frac{\partial \hat{w}}{\partial x} \right)^2 \, d\hat{x},$$

$$b_7 = a_{24} \times \frac{dL^2}{I_{33}},$$

$$b_8 = a_{25} \times \frac{dL^2}{I_{33}},$$

$$b_9 = a_{26} \times \frac{d^2 L^2}{I_{33}},$$

$$b_{10} = a_{27} \times \frac{d^2 L^2}{I_{33}},$$

$$b_{11} = a_{31} \times \frac{d^3 L^2}{I_{33}},$$

$$b_{12} = a_{32} \times \frac{d^3 L^2}{I_{33}},$$

$$b_{13} = a_{33} \times \frac{L^4}{I_{33}},$$

$$b_{14} = a_{34} \times \frac{dL^4}{I_{33}},$$

$$b_{15} = a_{35} \times \frac{d^2 L^4}{I_{33}},$$

$$b_{16} = a_{41} \times \frac{d^3 L^4}{I_{33}},$$

$$b_{17} = a_{42} \times \frac{L^4}{I_{33} d},$$

$$b_{18} = a_{52} \times \frac{I_{33}}{m^2 L^2},$$

$$b_{19} = a_{28} \times \frac{d}{m},$$

$$b_{20} = a_{29} \times \frac{d}{m},$$

$$b_{21} = a_{30} \times \frac{d^2}{m},$$

$$b_{22} = a_{31} \times \frac{d^2}{m},$$

$$b_{23} = a_{32} \times \frac{d^3}{m},$$

$$b_{24} = a_{40} \times \frac{d^3}{m}.$$
\[ a_{13}' = b_{13} \int_0^1 \varphi^2 d\hat{x}, \quad a_{14}' = b_{14} \int_0^1 \varphi^3 d\hat{x}, \]
\[ a_{15}' = b_{15} \int_0^1 \varphi^4 d\hat{x}, \quad a_{16}' = b_{16} \int_0^1 \varphi^5 d\hat{x}, \]
\[ a_{17}' = b_{17} \int_0^1 \varphi^6 d\hat{x}, \quad a_{18}' = b_{18} \int_0^1 \varphi^7 d\hat{x}, \]
\[ a_{19}' = b_{19} \int_0^1 \varphi^8 d\hat{x}, \quad a_{20}' = b_{20} \int_0^1 \varphi^9 d\hat{x}, \]
\[ a_{21}' = b_{21} \int_0^1 \varphi^{10} d\hat{x}, \quad a_{22}' = b_{22} \int_0^1 \varphi^{11} d\hat{x}, \]
\[ a_{23}' = b_{23} \int_0^1 \varphi^{12} d\hat{x}, \quad a_{24}' = b_{24} \int_0^1 \varphi^{13} d\hat{x}, \]
\[ a_{25}' = \frac{-N_L^2}{ET} \int_0^1 \varphi \varphi'' d\hat{x}. \]

**Appendix D**

The terms \( u_1(t) \), and \( u_2(t) \) are presented in Box I and \( \omega_1, \omega_2, v_1 \) and \( v_2 \) are presented as follows:

\[ \omega_1 = \frac{(-a_0 \omega^2 + 2a_0) V^4 a_{12} h}{v^2 (v^2 - \omega^2) \omega^2}, \]
\[ v_1 = \frac{(-a_0 \omega^2 + 2a_0) V^4 a_{12} h}{\omega^2 v^2 (v^2 - \omega^2)}, \]
\[ \omega_2 = \frac{1}{4 v^4 \omega^4 (v^6 - 3v^4 \omega^2 + 3v^2 \omega^4 - \omega^6)} \]
\[ (V^4 a_{12} h (4V^4 a_{12} \omega^2 h^2 \omega^2 + 4a_0 \omega^6 \text{omega}^4)
- 8a_0 \omega^4 \omega^6 + 4a_0 h^2 \omega^8 + 7V^2 a_{12} a_{10} h^2 \omega^6)
- 4V^2 a_{12} a_{10} h^2 \omega^4 + 6V^2 a_{12} a_{10} h^2 \omega^6
- V^2 a_{12} h \omega v^2 - 2V^2 a_{12} a_7 h^2 \omega^2
+ 4a_0 \omega^6 \omega^4 - 8a_0 v^4 \omega^6 + 4a_0 \omega^6 \omega^8) \]

\[ u_1(t) = \frac{h_{12} V^4 \cos(\omega t) \omega^2}{\omega^2 \omega^2} - \frac{h_{12} V^4 \cos(\omega t) \omega^2}{\omega^2 \omega^2} + h_{12} V^2, \]
\[ u_2(t) = \frac{h_{12} V^4 (h_{12} \cos(\omega t) \omega^2)}{\omega^2 \omega^2} - \frac{h_{12} V^4 (h_{12} \cos(\omega t) \omega^2)}{\omega^2 \omega^2} + h_{12} V^2 + h_{12} V^2. \]

**Box I**
Biographies

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